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Highly efficient microcrystalline silicon solar cells deposited from a pure SiH4 flow

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A time-resolved optical emission spectroscopic study identified transient behavior of the excited SiH emission in a parallel plate SiH4/H2 plasma. The transient behavior could be prevented by filling the background gas with H2 prior to plasma ignition. Applying this condition, state-of-the-art microcrystalline silicon (µc-Si:H) could be deposited irrespective of the applied H2 flow, ultimately demonstrated by a 9.5% efficient solar cell deposited from pure SiH4. The results are discussed in terms of SiH4 back diffusion: an initial diffusion flux of SiH4 from the reactor’s dead volume back into the plasma. © 2005 American Institute of Physics. [DOI: 10.1063/1.2152115]

Plasma deposition of the intrinsic microcrystalline silicon (µc-Si:H) film is a key process in the fabrication of highly efficient thin-film solar cells. High-quality µc-Si:H is deposited in a narrow regime close to the phase transition to amorphous growth, generally tuned by the feed gas dilution ratio \( R = \frac{[H_2]}{[\text{SiH}_4]} \). Commonly applied dilution ratios \( R \) range between approximately 10 and 300. These high values reflect the important role of \( H \) in the growth process. Nonetheless, recent studies revealed that it is possible to deposit µc-Si:H at much lower \( R \) by using the \( H \) that is created upon dissociation of SiH4. However, solar cells prepared under these conditions showed poor performance. Roschek et al. tried to solve this by grading the process flows during deposition, but still could not achieve state-of-the-art devices. These studies indicated that high \( R \) is an essential prerequisite for obtaining high-quality material.

In this letter, we will demonstrate that state-of-the-art µc-Si:H solar cells can be deposited from a pure SiH4 flow. We will make plausible that the previously reported drop of performance at low \( R \) was in fact caused by an initial diffusion flux of SiH4 from the reactor’s dead volume back into the plasma. Our findings are important from a fundamental point of view, demonstrating that the common belief that a high feed gas dilution ratio \( R \) is essential for obtaining high-quality µc-Si:H needs reinterpretation. Moreover, the newly developed process makes ultimate effective use of the SiH4 and strongly reduces the need for H2 as additional process gas, with obvious cost reduction promises for industry.

We conducted our study in the 13.56-MHz high pressure depletion regime, which has been developed recently for parallel plate plasma reactors to allow deposition of high-quality material at high rates. The reactor used for intrinsic µc-Si:H deposition, described in more detail elsewhere, encompassed a showerhead electrode for gas injection, and consisted of a volume of 11 liter, an interlede distance of 1.0 cm, and an electrode area of 150 cm². We applied a power of 0.5 W/cm², a pressure of 10 Torr (1.3 × 10^3 Pa), a SiH4 flow of up to 3.3 sccm (1.0 standard cm³ min⁻¹, or sccm, equals 7.4 × 10⁻⁷ mol s⁻¹), and an H2 flow of up to 1000 sccm. The substrate was kept at 196 ± 12 °C. These parameters, in particular the SiH4 flow, were optimized beforehand in a deposition series in order to make sure that the conditions were close to the phase transition to amorphous growth. A spectrometer equipped with a charge-coupled device (CCD) camera was used to measure the time resolved emission intensities of certain spectral lines.

Figure 1(a) shows the recorded emission intensity at 414.3 nm, originating from SiH⁺ created by electron impact dissociation of SiH4, during the first minute after plasma ignition for various values of \( R \). We also measured the emis-

![Figure 1. Recorded SiH⁺ emission as function of time for various values of the H2 dilution ratio R, in (a) the standard process and (b) the H2 background gas condition that prevents SiH4 back diffusion. Data is shown for R=0 with total flow ~2 sccm (closed circles), R=50 with total flow ~50 sccm (open circles), R=90 with total flow ~130 sccm (closed triangles), R=150 with total flow ~360 sccm (open triangles), and R=300 with total flow ~1000 sccm (closed stars). In (a), the R=0 case could not be recorded because the plasma did not ignite.](image-url)
The SiH4 diffusion flux should be proportional to the initial SiH4/H2 gas mixture, preventing the SiH4 back diffusion from happening. We realized that the SiH4 depletion in the plasma zone, the SiH4 depletion in the plasma zone, and the latter because of the too-high crystallinity. Quality: the former because of thick amorphous incubation layers and the latter because of the too-high crystallinity. Since our conditions are very close to the phase transition to amorphous growth, the SiH4 back diffusion mainly affects the Si-hydrogen transition, or the deposition on the amorphous side of the transition. Both cases lead to poor film quality; the former because of thick amorphous incubation layers and the latter because of the too-high crystallinity.

A background gas consisting predominantly of H2 would prevent the SiH4 back diffusion from happening. We realized this experimentally by first filling the entire reactor with H2. Then, after flushing the reactor for a short time period with the process flows of dilution R, the plasma was ignited. The flushing time was crucial to this method. If it was too short, a pure H2 plasma would be ignited. In this case, the SiH4 emission would gradually increase to its stable value. If it was too long, the SiH4 back diffusion process would be observed again to some degree. The time-resolved optical emission spectroscopy was used in this matter as a process control tool to determine the correct flushing times: Using values varying from 2 s at R=300 to 30 s at R=0, we obtained the stable SiH* emission signals of Fig. 1(b). It shows only the first 60 s after plasma ignition, in which initial SiH* emission enhancements of more than a factor of 2 were prevented. On longer time scales, the SiH* emission intensity decreased further by about 20%. We compensated for this by proportionally increasing the SiH2 flow during deposition.

Note that in the R=0 case the reactor consisted almost completely of H2 upon plasma ignition, since the flushing time was negligible compared to the gas residence time. The SiH* emission, hence SiH4 density, remained stable at this low value after ignition notwithstanding the applied pure SiH4 flow. This confirms our previous statement about the heavy SiH4 depletion.

Solar cells are very sensitive to changes in structure or optoelectronic properties of the mc-Si:H film and its interfaces. Therefore, to test the H2 background condition deposited material, intrinsic mc-Si:H layers were incorporated in p-i-n solar cell structures with an i-layer thickness of 1.0±0.1 μm. Texture-etched ZnO:Al-coated glass substrates served as transparent front contacts, while several 1×1 cm2 Ag back contacts defined the solar cell area. We applied the same deposition conditions as were used in the recording of Fig. 1(a) (the standard process) and Fig. 1(b) (the H2 background gas condition).

Figure 3 shows the solar cell properties obtained at various H2 dilution ratios R. For the standard process, solar cells deposited at R<100 showed poor performance, mainly due to lower fill factor and open circuit voltage, consistent with previous observations. In contrast, high-quality solar cells could be deposited at all H2 dilutions, down to R=0, when the H2 background gas condition was applied. We provided one sample, deposited at 0.4 nm/s, R=0, and a total gas flow of only 2.0 sccm, with a ZnO/Ag back contact for better light trapping. The cell showed excellent electronic performance with an open circuit voltage of 564 mV and a fill factor of 74.8%. Together with the short circuit current of 22.5 mA/cm2, the solar energy conversion efficiency was 9.5%. Depth-profiled Raman spectroscopy measurements.

FIG. 2. Schematic representation of the sequence of processes that occur after plasma ignition: (a) stable situation before plasma ignition, (b) plasma ignition and initial SiH4 depletion in the plasma zone, (c) SiH4 back diffusion, (d) purging, (e) stable situation after plasma ignition.
revealed a homogeneously structured film crystallinity around 70%.

In summary, the aforementioned results lead to a reinterpretation of the role of H₂ dilution: The high H₂ flow generally applied during deposition of μc-Si:H is needed to suppress SiH₄ back diffusion. When it is suppressed in other ways, e.g., by applying a H₂ background prior to plasma ignition, high-quality μc-Si:H can be deposited irrespective of the applied H₂ flow.

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